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## **TC 3700 Inventor Search Program**

See attached inventor searches for applications and/or patents to help resolve questions of overlapping subject matter. These searches are provided as an initial examination aid: examiners should perform updated or expanded PALM or EAST inventors searches as appropriate.

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**Serial Number:**      10/530277

**1.) See attached printout of inventors listed in  
PALM**

**2.) See attached EAST Inventor Search  
Printout shows Inventor search terms**

US 20060009127 A1	US- PGPUB	20060112	Method for estimating polishing profile or polishing amount, polishing method and polishing apparatus	451/5	451/41; 451/8	Sakurai, Kunihiko et al.
US 20050227596 A1	US- PGPUB	20051013	Polishing apparatus	451/285		Katsuoka, Seiji et al.
US 20050193156 A1	US- PGPUB	20050901	Data processing system	710/260		Inoue, Masafumi et al.
US 20050159082 A1	US- PGPUB	20050721	Polishing apparatus	451/11		Sakurai, Kunihiko et al.
US 20050118935 A1	US- PGPUB	20050602	Substrate holding apparatus	451/41	451/285; 451/402	Togawa, Tetsuji et al.
US 20050107015 A1	US- PGPUB	20050519	Substrate holding device and polishing device	451/285		Togawa, Tetsuji et al.
US 20050015975 A1	US- PGPUB	20050127	Method and mounting component on a circuit board	29/840	29/834	Inoue, Masafumi et al.
US 20040209560 A1	US- PGPUB	20041021	Substrate polishing machine	451/288		Togawa, Tetsuji et al.
US 20040180070 A1	US- PGPUB	20040916	Insecticide transpiration apparatus	424/405		Inoue, Masafumi et al.
US 20040137823 A1	US- PGPUB	20040715	Polishing apparatus	451/5	451/11	Sakurai, Kunihiko et al.
US 20040121704 A1	US- PGPUB	20040624	Vertically adjustable chemical mechanical polishing head having a pivot mechanism and method for use thereof	451/5	451/41	Sakurai, Kunihiko et al.
US 20040085701 A1	US- PGPUB	20040506	Method of mounting component on a circuit board	361/135	29/740; 29/832	Inoue, Masafumi et al.
US 20030223887 A1	US- PGPUB	20031204	Fluid apparatus	417/269	91/499; 92/12.2	Kawano, Shigeru et al.
US 20030202835 A1	US- PGPUB	20031030	Printing device provided with cutter to cut recording paper	400/621		Sakurai, Kunihiko et al.
US 20030160062 A1	US- PGPUB	20030828	Insecticide transpiration apparatus	222/52		Inoue, Masafumi et al.
US 20030156951 A1	US- PGPUB	20030821	Compressor	417/269	417/360	Kamiya, Hirokazu et al.
US 20030134580 A1	US- PGPUB	20030717	Polishing apparatus	451/56	451/287; 451/443	Sakurai, Kunihiko et al.
US 20030086792	US- PGPUB	20030508	Compressor	417/222.2	417/269; 417/312	Kamiya, Hirokazu et al.

A1						
US 20030077989 A1	US- PGPUB	20030424	Polishing system with air exhaust system	451/65		Isobe, Soichi et al.
US 20030064237 A1	US- PGPUB	20030403	(Meth)acrylic crosslinked fine particles and method of manufacturing the same	428/500		Oishi, Hideki et al.
US 20020137876 A1	US- PGPUB	20020926	Process for producing amino resin particles	528/258	524/843; 524/879; 525/328.7; 525/398; 525/401; 528/243; 528/254	Yamamoto, Yasuhiro et al.
US 20020124373 A1	US- PGPUB	20020912	Polishing apparatus	29/281.1		Katsuoka, Seiji et al.
US 20020112348 A1	US- PGPUB	20020822	Component mounting method	29/854	29/846; 29/860	Inoue, Masafumi et al.
US 20020083570 A1	US- PGPUB	20020704	Component mounting system and mounting method	29/428	29/592.1	Inoue, Masafumi et al.
US 20020046462 A1	US- PGPUB	20020425	Component mouter and mounting method	29/834	29/739; 29/832	Inoue, Masafumi et al.
US 20020045410 A1	US- PGPUB	20020418	Polishing apparatus	451/57	451/159; 451/160; 451/58	Sakurai, Kunihiko et al.
US 20020042246 A1	US- PGPUB	20020411	Substrate holding apparatus	451/288		Togawa, Tetsuji et al.
US 20020025764 A1	US- PGPUB	20020228	Polishing apparatus	451/41	451/283; 451/287; 451/290; 451/54	Katsuoka, Seiji et al.
US 20020009954 A1	US- PGPUB	20020124	Polishing apparatus	451/57		Togawa, Tetsuji et al.
US 20010051268 A1	US- PGPUB	20011213	Grain aggregate and producing method thereof, and light- diffusing agent	428/402	264/13; 428/327	Iriguchi, Jiro et al.
US 6983538 B2	USPAT	20060110	Method of mounting component on a circuit board	29/840	228/8; 228/9; 29/593; 29/739; 29/833; 700/116	Inoue, Masafumi et al.
US 6957950 B2	USPAT	20051025	Compressor with compact screw connected housing and adjustable mounting means	417/222.1	417/269; 417/360; 92/12.2; 92/91	Kamiya, Hirokazu et al.
US 6953390 B2	USPAT	20051011	Polishing apparatus	451/56	451/443; 451/444; 451/57	Sakurai, Kunihiko et al.
US 6942541	USPAT	20050913	Polishing apparatus	451/5	451/65	Togawa, Tetsuji et al.

B2						
US 6926902 B2	USPAT	20050809	Insecticide transpiration apparatus	424/409	424/405; 424/406; 424/408; 424/417; 43/124; 43/132.1; 514/532	Inoue; Masafumi et al.
US 6918814 B2	USPAT	20050719	Polishing apparatus	451/5	451/173; 451/174; 451/287; 451/288; 451/41; 451/6; 451/60	Katsuoka; Seiji et al.
US 6878044 B2	USPAT	20050412	Polishing apparatus	451/67	269/60; 451/332; 451/41	Sakurai; Kunihiro et al.
US 6852019 B2	USPAT	20050208	Substrate holding apparatus	451/288	451/388	Togawa; Tetsuji et al.
US 6821037 B2	USPAT	20041123	Printing device provided with cutter to cut recording paper	400/621	358/1.1; 400/593	Sakurai; Kunihiro et al.
US 6786704 B2	USPAT	20040907	Compressor with single shaft support	417/222.2	417/222.1; 417/269; 92/71	Kamiya; Hirokazu et al.
US 6783427 B2	USPAT	20040831	Polishing system with air exhaust system	451/5	134/902; 451/285; 451/41; 451/65; 451/8; 451/9; 454/187	Isobe; Soichi et al.
US 6757966 B2	USPAT	20040706	Component mounting system and mounting method	29/840	228/105; 228/9; 29/712; 29/721; 29/740; 29/833; 700/117	Inoue; Masafumi et al.
US 6729532 B2	USPAT	20040504	Component mounting method	228/254	228/180.1; 228/180.22; 29/840; 29/842; 29/844; 382/145	Inoue; Masafumi et al.
US 6682408 B2	USPAT	20040127	Polishing apparatus	451/67	451/285; 451/287; 451/41; 451/65; 451/66	Sakurai; Kunihiro et al.
US 6610818 B2	USPAT	20030826	Process for producing amino resin particles	528/480	523/205; 523/208; 524/495; 524/597; 528/490; 528/492;	Yamamoto; Yasuhiro et al.

					528/498; 528/499; 528/502A; 528/502F	
US 6610405 B2	USPAT	20030826	Grain aggregate and producing method thereof, and light- diffusing agent	428/403	427/201; 427/222; 427/226; 427/447; 428/407	Iriguchi; Jiro et al.
US 6578891 B1	USPAT	20030617	Substrate holder and substrate transfer apparatus using the same	294/64.1	294/907; 414/941	Suzuki; Hiroo et al.
US 6413146 B1	USPAT	20020702	Polishing apparatus	451/5	451/173; 451/174; 451/288; 451/41; 451/6; 451/60	Katsuoka; Seiji et al.
US 6409576 B1	USPAT	20020625	Polishing apparatus	451/6	451/10; 451/11; 451/287; 451/41; 451/54	Oguri; Syozo et al.
US 6402597 B1	USPAT	20020611	Polishing apparatus and method	451/56	451/53	Sakurai; Kunihiko et al.
US 6358131 B1	USPAT	20020319	Polishing apparatus	451/287	451/285	Sakurai; Kunihiko et al.
US 6358128 B1	USPAT	20020319	Polishing apparatus	451/67	451/287; 451/332; 451/333	Sakurai; Kunihiko et al.
US 6354922 B1	USPAT	20020312	Polishing apparatus	451/67	451/288; 451/73	Sakurai; Kunihiko et al.
US 6332826 B1	USPAT	20011225	Polishing apparatus	451/5	451/173; 451/287; 451/288; 451/41; 451/6; 451/60	Katsuoka; Seiji et al.
US 6326712 B1	USPAT	20011204	Magnetic bearing device	310/90.5	310/68B; 324/207.12; 324/207.26	Nakazawa; Toshiharu et al.
US 6285782 B1	USPAT	20010904	Mounting apparatus, recognition device and recognition method for electronic component	382/145		Inoue; Masafumi et al.
US 6283822 B1	USPAT	20010904	Polishing apparatus	451/5	451/288; 451/41	Togawa; Tetsuji et al.
US 6227954 B1	USPAT	20010508	Polishing apparatus	451/285	451/287; 451/288; 451/443; 451/451	Togawa; Tetsuji et al.
US 5961380 A	USPAT	19991005	Robotic transport apparatus	451/339	451/41; 451/914	Togawa; Tetsuji et al.
US 5893794 A	USPAT	19990413	Polishing apparatus having robotic transport apparatus	451/67	451/339; 451/914	Togawa; Tetsuji et al.

US 5860847 A	USPAT	19990119	Polishing apparatus	451/10	257/E21.528; 451/285; 451/287; 451/41	Sakurai; Kunihiro et al.
US 5839947 A	USPAT	19981124	Polishing apparatus	451/288	451/287	Kimura; Norio et al.
US 5830045 A	USPAT	19981103	Polishing apparatus	451/288	451/5; 451/67; 451/73	Togawa; Tetsuji et al.
US 5647792 A	USPAT	19970715	Polishing apparatus	451/285	269/236; 451/287; 451/288	Katsuoka; Seiji et al.
US 5643067 A	USPAT	19970701	Dressing apparatus and method	451/444	451/211; 451/270; 451/271; 451/287; 451/56	Katsuoka; Seiji et al.
US 5343913 A	USPAT	19940906	Wood treating method and apparatus	144/380	144/2.1; 144/271; 144/361; 425/385	Tanahashi; Mitsuhiko et al.
US 5247975 A	USPAT	19930928	Wood treating method and apparatus	144/271	144/2.1; 144/361; 144/380; 425/385	Tanahashi; Mitsuhiko et al.
US 5226437 A	USPAT	19930713	Washing apparatus	134/104.1	134/140; 134/902	Kamikawa; Yuji et al.